Investigation of Atmospheric Plasma Processing in Dielectric Barrier Discharge

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INTRODUCTION

RESULTS

Effect of Discharge Gap



Goal: Investigation of plasma parameters in DBD reactor at different discharge gap and dielectric material

COMPUTATIONAL METHODS:

Model equations

Figure 3. Plot of Argon mass fraction (a) $0.5*10^{-4}$ m; (c) $6*10^{-4}$ m and Total capacitive power deposition (b) $0.5*10^{-4}$ m; (d) $6*10^{-4}$ m

Type of material



$$\frac{\partial n_e}{\partial t} + \nabla \Gamma_e = R_e - (u, \nabla)n_e$$
$$\frac{\partial n_e}{\partial t} + \nabla \Gamma_e + E \Gamma_e = S_{en} - (u, \nabla)n_e + (Q + Q_{gen})/c$$
$$\Gamma_e = -(\mu_{en}, E)n_e - D_{en}, \nabla n_e$$

 n_e – electron density; n_{ϵ} – electron energy density ; Γ -particle flux density; S -source and lose items of particles; μ_e – electron mobility; μ_e – electron mobility; μ_{ϵ} – electron energy mobility; D-diffusion coefficient; E-electric field.

Geometrical condition

Variable	Value	Units
Length	0.1	m
Width	0.02	m
Area	0.002	m ²

Figure 4. Plot of Argon mass fraction at different types of dielectric material (a) Aluminum; (b) Silicon; (c) Acrylic plastic

CONCLUSIONS:

- Power consumption was less in small discharge gap
- Generated plasma is unstable with increasing the discharge gap.



Maximum value of mass fraction of Argon is observed in silicon than others.

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